

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Leonard Forbes et al.
Title: SILICON CARBIDE GATE TRANSISTOR AND FABRICATION PROCESS
Docket No.: 303.326US1
Filed: July 29, 1997
Examiner:

Serial No.: 08/903,486
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Group Art Unit: 1104



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Assistant Commissioner for Patents
Washington, D.C. 20231

We are transmitting herewith the following attached items (as indicated with an "X"):

- ☒ A return postcard.
- ☒ An Information Disclosure Statement (1 pgs.), Form 1449 (7 pgs.), and copies of 97 cited references.

Please consider this a PETITION FOR EXTENSION OF TIME for sufficient number of months to enter these papers and please charge any additional required fees or credit overpayment to Deposit Account No. 19-0743.

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this Transmittal Letter and the paper, as described above, are being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on this 19 day of March, 1998.

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(GENERAL)